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INFORMATION DISCLOSURE STATEMENT

(Use several sheets if necessary)

APPLICANTS
Yoshihito NARITA et al.

FILING DATE
February 19, 2002

U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS

FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS
Aullab	1 JP A 2000-215499 (w/abstract)	08/04/2000	Japan		
	2 JP A 2000-132856 (w/abstract)	05/12/2000	Japan		
	3 JP A 2000-223767 (w/abstract)	08/11/2000	Japan		

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)

Aullab	4	Yatsui et al., "Subwavelength-sized phase-change recording with a silicon planar apertured probe", SPIE, Vol. 3791, pages 76-84, July 1999
	5	Lee et al., "Nanometric aperture arrays fabricated by wet and dry etching of silicon for near-field optical storage application", J. Vac. Sci. Technol. B, Vol. 17, Number 6, pages 2462-2466, Nov/Dec 1999
	6	Yatsui et al., "High-density-speed optical near-field recording-reading with a pyramidal silicon probe on a contact slider", OPTICS LETTERS, Vol. 25, No. 17, pages 1279-1281, September 2000

EXAMINER

Akrm Enayet Ullah

DATE CONSIDERED

Feb. 09 - 2004

Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Date: July 18, 2002